

ABSTRACT

The invention relates to an inspection system for process equipment for treating substrates, such as, for instance, semiconductor wafers or flat panel displays. The system is provided with a wireless sensor with which the interior of the process device can be inspected. The sensor is provided with a transmitter to transfer a signal, during inspection of the interior of the process device, to a receiver disposed outside the process device. The wireless sensor is arranged on a support having substantially the same dimensions as the substrates to be treated.

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